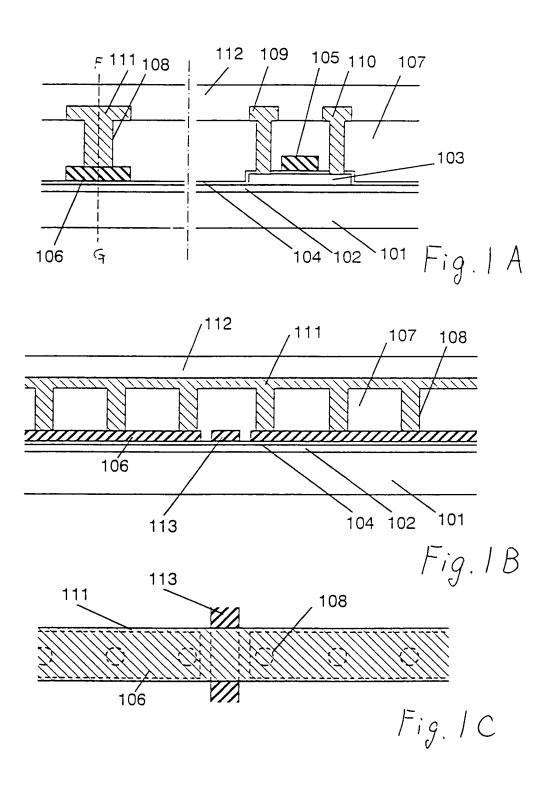
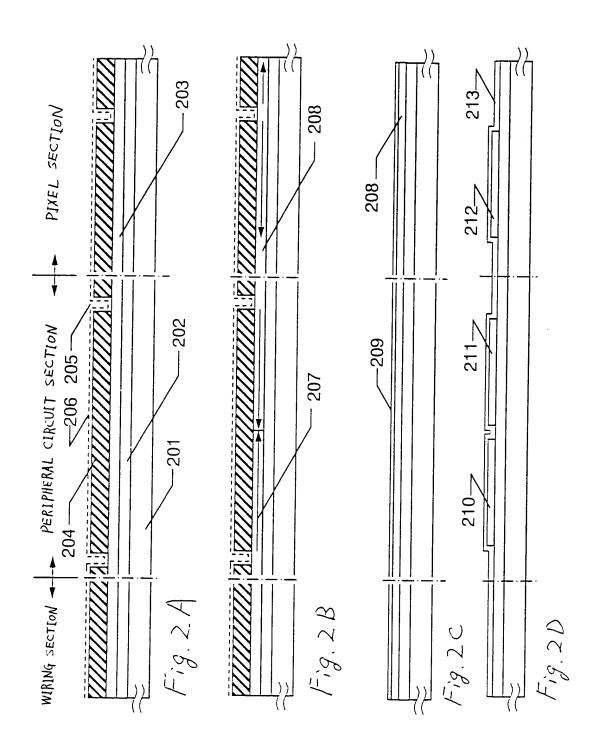
Appln No.: New DIV Appln. Page 1 of 5
Applicant(s): Jun Koyama et al.
SEMICONDUCTOR DEVICE AND MANUFACTURING
METHOD THEREOF



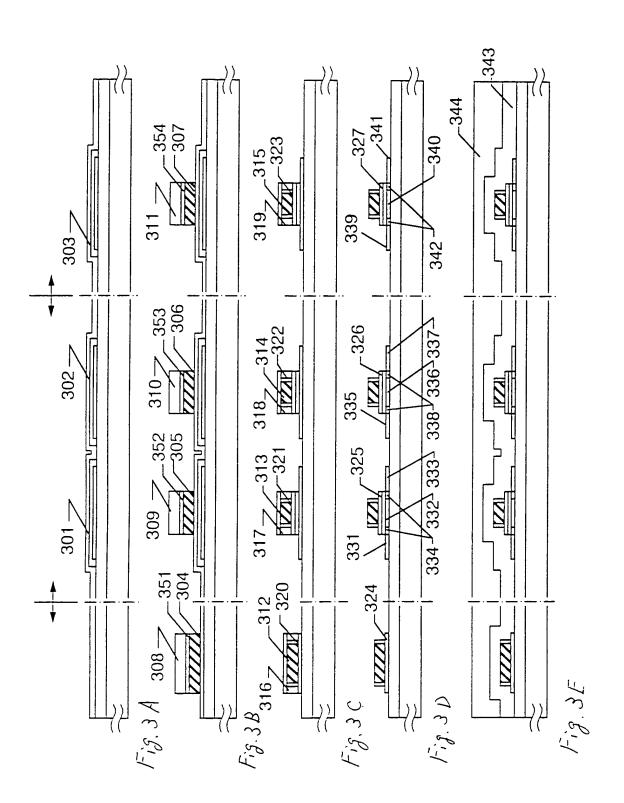
Appln No.: New DIV Appln. Pag Applicant(s): Jun Koyama et al. SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF



Page 3 of 5

Appln No.: New DIV Appln. Pag Applicant(s): Jun Koyama et al. SEMICONDUCTOR DEVICE AND MANUFACTURING

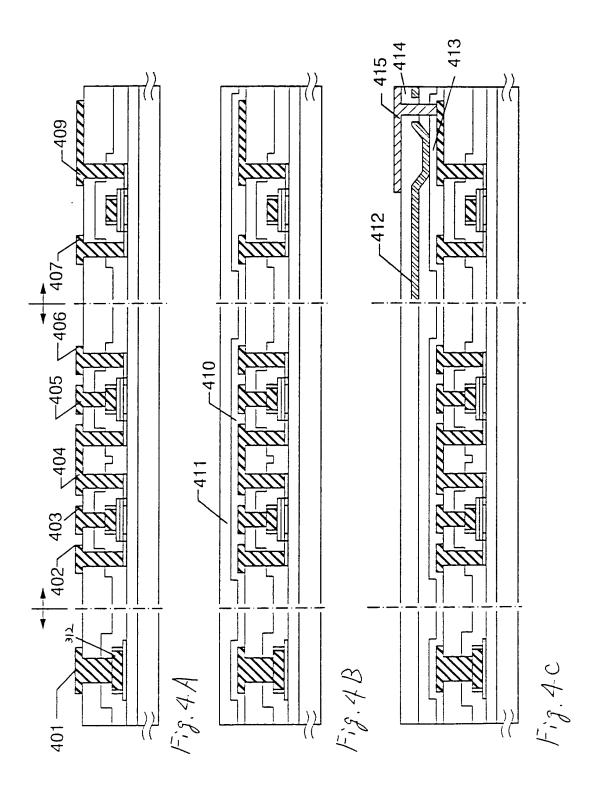
METHOD THEREOF



Page 4 of 5

Appln No.: New DIV Appln. Pag
Applicant(s): Jun Koyama et al.
SEMICONDUCTOR DEVICE AND MANUFACTURING

METHOD THEREOF



Page 5 of 5

Appln No.: New DIV Appln. Pag
Applicant(s): Jun Koyama et al.
SEMICONDUCTOR DEVICE AND MANUFACTURING

METHOD THEREOF

